

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

icant:

Frank Y. Xu et al.

App. No.:

10/763,885

GPAU:

1752

Filing Date:

01/23/2004

Examiner:

Amanda C. Walke

Dkt. No.:

P113-55-03

Conf. No.:

6002

For: M

MATERIALS AND METHODS FOR IMPRINT LITHOGRAPHY

### INFORMATION DISCLOSURE STATEMENT

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#### Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

$\boxtimes$	Form(s)	PTO/SB/08A	and/or	PTO/SB/08B	or	PTO/1449
$\mathbf{Z}\mathbf{Z}$	TOTH (D)	I IO/ DD/ OOM	and, or	110,000,000	$\circ$	110/1442

□ Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed:

before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

the Commissioner is hereby authorized to charge any fees which may be required, or credit any overpayment, to Deposit Account Number 502650.

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Date:

Respectfully Submitted,

Kenneth C. Brooks,

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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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17 Sheet of

Complete if Known					
Application Number	10/763,885				
Filing Date	01/23/2004				
First Named Inventor	Xu et al.				
Group Art Unit	1752				
Examiner Name	Amanda C. Walke				
Attorney Docket Number	P113-55-03				

Examiner	Cite	U.S. Patent Do		Name of Patentee or Applicant	Date of Publication of	Pages, Columns, Lines,
Initials*	No.1	Number	Kind Code <sup>2</sup> (if known)	of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	B1	3,527,062		Bilinski et al.	09-08-1970	
	B2	3,783,520		King	01-08-1974	
	B3	3,807,027		Heisler	04-30-1974	
	B4	3,807,029		Troeger	04-30-1974	
	B5	3,811,665		Seelig	05-21-1974	
	B6	4,062,600		Wyse	12-13-1977	
	B7	4,070,116		Frosch et al.	01-24-1978	
	B8	4,098,001		Watson	07-04-1978	
	B9	4,119,688		Hiraoka	10-10-1978	
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	B11	4,155,169		Drake et al.	05-22-1979	
	B12	4,201,800		Alcorn et al.	05-06-1980	
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	B14	4,267,212		Sakawaki	05-12-1981	
	B15	4,326,805		Feldman et al.	04-27-1982	
	B16	4,337,579		De Fazio	07-06-1982	
	B17	4,355,469		Nevins et al.	10-26-1982	
	B18	4,414,750		De Fazio	11-15-1983	
	B19	4,426,247		Toshiakai et al.	01-17-1984	
	B20	4,440,804		Milgram	04-03-1984	
	B21	4,451,507		Beltz et al.	05-29-1994	
	B22	4,507,331		Hiraoka	03-02-1985	
	B23	4,544,572		Sandvig et al.	10-01-1985	
	B24	4,552,832		Blume et al.	11-12-1985	
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	B28	4,657,845		Frechet et al.	04-04-1987	
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	B34	4,808,511		Holmes	02-28-1989	
Examiner				·	Date	
Signature			<u> </u>		Considered	

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>&</sup>lt;sup>1</sup>Unique citation designation number. <sup>2</sup>See attached Kinds of U.S. Patent Documents. <sup>3</sup>Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

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Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number. Complete if Known Substitute for form 1449A/PTO **Application Number** 10/763,885 INFORMATION DISCLOSURE **Filing Date** 01/23/2004 STATEMENT BY APPLICANT **First Named Inventor** Xu et al. Group Art Unit 1752 (use as many sheets as necessary) **Examiner Name** Amanda C. Walke 17 Sheet of Attorney Docket Number P113-55-03

		T	<del></del>	U.S. PATENT DOCUMEN	19	
Examiner nitials*	Cite No.1	U.S. Patent [	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	B35	4,826,943		Ito et al.	05-02-1989	
	B36	4,846,931		Gmitter et al.	07-11-1989	
	B37	4,848,911		Uchida et al.	07-18-1989	
	B38	4,857,477		Kanamori	08-15-1989	
	B39	4,883,561		Gmitter et al.	11-28-1989	
	B40	4,891,303		Garza et al.	01-02-1990	
	B41	4,908,298		Hefferon et al.	03-13-1990	
	B42	4,919,748		Bredbenner et al.	04-24-1990	
<u>.</u>	B43	4,921,778		Thackeray et al.	05-01-1990	
	B44	4,929,083		Brunner	05-29-1990	
	B45	4,931,351		McColgin et al.	06-05-1990	
	B46	4,959,252		Bonnebat et al.	09-25-1990	·
	B47	4,964,945		Calhoun	10-23-1990	
	B48	4,976,818		Hashimoto et al.	12-11-1990	
	B49	4,980,316		Huebner	12-25-1990	
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	B51	5,053,318		Gulla et al.	10-01-1991	
	B52	5,063,321		Carter	11-05-1991	
	B53	5,071,694		Uekita et al.	12-10-1991	
	B54	5,072,126		Progler	12-10-1991	
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	B66	5,198,326		Hashimoto et al.	03-30-1993	
	B67	5,204,739		Domenicali	04-20-1993	
	B68	5,206,983		Guckel et al.	05-04-1993	N . W . W . W
xaminer Signature					Date Considered	

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PTO/SB/08A (08-00)

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Substitute	for form 1449A/PT(	)		Complete if Known		
				Application Number	10/763,885	
INFO	<b>RMATION I</b>	DISCL	OSURE	Filing Date	01/23/2004	
STAT	<b>TEMENT BY</b>	<b>APPL</b>	LICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(	use as many sheet	s as neces	sary)	Examiner Name	Amanda C. Walke	
Sheet	3	of	17	Attorney Docket Number	P113-55-03	

	1	U.S. Patent Do	cument	T	Data of Dublication of	Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	B69	5,212,147		Sheats	05-18-1993	
	B70	5,234,793		Sebald et al.	08-10-1993	
	B71	5,240,550		Boehnke et al.	08-31-1993	-
	B72	5,240,878		Fizsimmons et al.	08-31-1993	
	B73	5,242,711		DeNatale et al.	09-07-1993	<del>"</del>
	B74	5,244,818		Jokerst et al.	09-14-1993	
	B75	5,259,926		Kuwabara et al.	09-09-1993	
	B76	5,270,984	Α	Mine	12-14-1993	
	B77	5,277,749		Griffith et al.	01-11-1994	
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	B79	5,318,870		Hartney	06-07-1994	
	B80	5,324,683		Fitch et al.	06-28-1994	
	B81	5,328,810		Lowrey et al.	07-12-1994	
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	B86	5,374,454		Bickford et al.	12-20-1994	
	B87	5,376,810		Hoenk et al.	12-27-1994	
	B88	5,380,474		Rye et al.	01-10-1995	
	B89	5,392,123		Marcus et al.	02-21-1995	
	B90	5,417,802		Obeng	05-23-1995	
	B91	5,421,981		Leader et al.	06-06-1995	
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	B94	5,425,964		Southwell et al.	06-20-1995	
	B95	5,431,777		Austin et al.	07-11-1995	
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	B101	5,480,047		Tanigawa et al.	01-02-1996	
		INTENTIONAL	BLANK			
Examiner					Date	
Signature					Considered	

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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P113-55-03

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Complete if Known Substitute for form 1449A/PTO **Application Number** 10/763,885 **INFORMATION DISCLOSURE Filing Date** 01/23/2004 STATEMENT BY APPLICANT **First Named Inventor** Xu et al. **Group Art Unit** 1752 (use as many sheets as necessary)

17

**Examiner Name** 

Attorney Docket Number

	<u> </u>	U.S. Patent Do		J.S. PATENT DOCUMENTS		Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	B102	5,515,167		Ledger et al.	05-07-1996	
	B103	5,523,878		Wallace et al.	06-04-1996	
	B104	5,527,662		Hashimoto et al.	06-18-1996	
	B105	5,545,367		Bae et al.	08-13-1996	
	B106	5,566,584		Briganti	10-22-1996	
	B107	5,633,505		Chung et al.	05-27-1997	
	B108	5,654,238		Cronin et al.	08-05-1997	
	B109	5,670,415		Rust	09-23-1997	
	B110	5,700,626		Lee et al.	12-23-1997	
	B111	5,723,176		Keyworth et al.	03-03-1998	
	B112	5,724,145		Kondo et al.	03-03-1998	
	B113	5,725,788		Maracas et al.	03-10-1998	
	B114	5,736,424		Prybyla et al.	04-07-1998	
	B115	5,743,998		Park	04-28-1998	
	B116	5,747,102		Smith et al.	05-05-1998	
	B117	5,753,014		Van Rijn	05-19-1998	
	B118	5,760,500		Kondo et al.	06-02-1998	
	B119	5,776,748		Singhvi et al.	07-07-1998	
	B120	5,779,799		Davis	07-14-1998	
	B121	5,802,914	į	Fassler et al.	09-08-1998	
	B122	5,855,686	}	Rust	01-05-1999	
	B123	5,877,036		Kawai	03-02-1999	
	B124	5,877,861		Ausschnitt et al.	03-02-1999	
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	B127	5,907,782		Wu	05-25-1999	
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	B129	5,926,690		Toprac et al.	07-20-1999	
	B130	5,937,758		Maracas et al.	08-17-1999	
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	B132	5,948,219		Rohner	09-07-1999	
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	B135	6,033,977		Gutsche et al.	03-07-2000	
Examiner Signature					Date Considered	

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				Application Number	10/763,885	
INFO	RMATION D	ISCI	LOSURE	Filing Date	01/23/2004	
STAT	<b>FEMENT BY</b>	<b>APP</b>	LICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke	
Sheet	5	of	17	Attorney Docket Number	P113-55-03	

				J.S. PATENT DOCUMENTS	S	
Examiner Initials*	Cite No.1	U.S. Patent Doo	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	B136	6,035,805		Rust	03-14-2000	
	B137	6,038,280		Rossiger et al.	03-14-2000	
	B138	6,046,056		Parce et al.	04-04-2000	
	B139	6,051,345		Huang	04-18-2000	
	B140	6,074,827		Nelson et al.	06-13-2000	
	B141	6,091,485		Li et al.	07-18-2000	
	B142	6,096,655		Lee et al.	08-01-2000	
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	B148	6,150,680		Eastman et al.	11-21-2000	
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	B150	6,180,239	B1	Whitesides et al.	01-30-2001	
·	B151	6,188,150	B1	Spence	02-13-2001	
	B152	6,204,922	B1	Chalmers	03-20-2001	
	B153	6,218,316	B1	Marsh	04-17-2001	
	B154	6,245,581	B1	Bonser et al.	06-12-2001	
	B155	6,274,294	B1	Hines	08-14-2001	
	B156	6,326,627	B1	Putvinski et al.	12-04-2001	
	B157	6,329,256	B1	Ibok	12-11-2001	
	B158	6,355,198	B1	Kim et al.	03-12-2002	
	B159	6,387,783		Furukawa et al.	05-14-2002	
	B160	6,388,253	B1	Su	05-14-2002	
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	B162	6,411,010	B1	Suzuki et al.	06-25-2002	
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	B166	6,482,742	B1	Chou	11-19-2002	
	B167	6,489,068	B1	Kye	12-03-2002	
	B168	6,495,624	B1	Brown, James F.	12-17-2002	
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Examiner Signature		<del></del>	·	·	Date Considered	<del>- 11 - 12 - 1</del>

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Sheet 6 of 17

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	B170	6,534,418	B1	Plat et al.	03-18-2003	
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	B172	6,561,706		Singh et al.	05-13-2003	
	B173	6,565,928	B2	Sakamoto et al.	05-20-2003	
	B174	6,632,742	B2	Yang et al.	10-14-2003	
	B175	6,635,581	B2	Wong	10-21-2003	
	B176	6,646,662	B1	Nebashi et al.	11-11-2003	
	B177	6,677,252	B2	Marsh	01-13-2004	
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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 7 of 17

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Complete if Known					
Application Number	10/763,885				
Filing Date	01/23/2004				
First Named Inventor	Xu et al.				
Group Art Unit	1752				
Examiner Name	Amanda C. Walke				
Attorney Docket Number	P113-55-03				

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Examiner Initials*	Cite No.1	U.S. Patent Do	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
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Complete if Known Substitute for form 1449A/PTO **Application Number** 10/763,885 INFORMATION DISCLOSURE Filing Date 01/23/2004 STATEMENT BY APPLICANT **First Named Inventor** Xu et al. 1752 **Group Art Unit** (use as many sheets as necessary) **Examiner Name** Amanda C. Walke 17 Sheet of Attorney Docket Number P113-55-03

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<u> </u>	B230	EP	244884		Ponjee	03-03-1987		
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Substitu	te for form 1449B/	РТО	-	Complete if Known		
				Application Number	10/763,885	
INFO	PRMATION	DISC	CLOSURE	Filing Date	01/23/20904	
STATEMENT BY APPLICANT				First Named Inventor	Xu et al.	
				Group Art Unit	1752	
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Sheet	9	of	17	Attorney Docket Number	P113-55-03	

ſ	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS							
	Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>				
		B249	Ab	٠				
I	<del>\</del>		Abstract of Japanese Patent 02-24848, January 26, 1990					
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Substitu	ute for form 1449B/I	PTO		Complete if Known		
				Application Number	10/763,885	
INF	ORMATION	DISC	LOSURE	Filing Date	01/23/2004	
STA	TEMENT E	BY API	PLICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke	
Sheet	10	of	17	Attorney Docket Number	P113-55-03	

J	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS								
	Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>					
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INF	ORMATION	DIS	CLOSURE	Filing Date	01/23/2004	
STATEMENT BY APPLICANT				First Named Inventor	Xu et al.	
				Group Art Unit	1752	
	(use as many shee	ts as n	ecessary)	Examiner Name	Amanda C. Walke	
Sheet	11	of	17	Attorney Docket Number	P113-55-03	

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INFORMATION DISCLOSURE				Filing Date	01/23/2004	
STA	STATEMENT BY APPLICANT			First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)		Examiner Name	Amanda C. Walke			
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				Group Art Unit	1752	
	(use as many sheets as necessary)			Examiner Name	Amanda C. Walke	
Sheet	14	of	17	Attorney Docket Number	P113-55-03	

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Examiner		Date	
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Substitute for form 1449B/PTO				Complete if Known		
				Application Number	10/763,885	
<b>INFORMATION DISCLOSURE</b>				Filing Date	01/23/2004	
STA	STATEMENT BY APPLICANT			First Named Inventor	Xu et al.	
			Group Art Unit	1752		
(use as many sheets as necessary)		Examiner Name	Amanda C. Walke			
Sheet	15	of	17	Attorney Docket Number	P113-55-03	

OTHER PRIOR	R ART - N	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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Sheet	16	of	17	Attorney Docket Number	P113-55-03	

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS					
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